

Special Issue

Next-Generation Piezoelectric Films: Materials, Fabrication, and Applications

Message from the Guest Editor

Piezoelectric films have been extensively utilized across a variety of fields, particularly in piezoelectric MEMS sensors, actuators, and energy harvesting systems. Recent scientific breakthroughs have not only improved the intrinsic performance of these films, but have also accelerated progress in multiple interconnected domains. These include advances in material science, innovative deposition and measurement methodologies, device design strategies, and micro-fabrication techniques tailored for piezoelectric MEMS devices. In light of these developments, this Special Issue of *Micromachines* seeks to establish a dedicated platform for compiling the most recent research outcomes concerning piezoelectric films. By bringing together diverse and cutting-edge research, this Special Issue aims to foster productive dialogue between academic and industrial communities, thereby promoting further innovation and technological advancement in the field of high-performance piezoelectric film technology.

Guest Editor

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